

CLAIM AMENDMENTS:

Please amend Claims 1-12 as follows:

1. (Currently Amended) A method for producing an ink jet recording head including a head member having a hydrophilically treated surface, comprising steps of:

a first step for forming, on a substrate, a solid layer composed of soluble resin and having a pattern for constituting a liquid flow path having a surface for being hydrophilically treated;

a second step for forming a hydrophilic film with a side thereof in contact with said surface of an inorganic film by low temperature film formation so as to cover said solid layer;

a third step for forming a layer of a head forming material so as to cover said inorganic film said head member on said hydrophilic film; and

removing a part of said inorganic film for forming a discharge port;  
and

a fourth step for removing said solid film to expose said side of said hydrophilic film thereby forming a liquid flow path communicating with the discharge port.

2. (Currently Amended) A method according to claim 1, wherein said low temperature hydrophilic film formation is executed by sputtering, CVD or vapor deposition.

3. (Currently Amended) A method according to claim 1, wherein said inorganic hydrophilic film is composed of SiN, SiO<sub>2</sub>, Al<sub>2</sub>O<sub>3</sub>, Ti, Ta, Cu, Ag or ITO.

4. (Currently Amended) A method according to claim 1, wherein the layer of said head-forming member is formed of a material having an ink repellent property.

5. (Currently Amended) A method according to claim 4, wherein the layer of said head-forming member material is composed of an ink-repellent settable resin.

6. (Currently Amended) A method according to claim 1, wherein the layer of said head-forming material is composed of an inorganic material.

7. (Currently Amended) A method according to claim 1, wherein said head is of an edge shooter type in which said an ink discharge port is provided on an end face of said a head substrate.

8. (Currently Amended) A method according to claim 1, wherein said inorganic film removing fourth step is executed by after cutting through said inorganic film together with said substrate head member, said film, and said layer.

9. (Currently Amended) A method according to claim 1, wherein said head is of a side shooter type in which said an ink discharge port is provided toward above said a head substrate.

10. (Currently Amended) A method according to claim 1, wherein the layer of said head forming said head member comprises material is composed of resin and said inorganic film removing fourth step is executed by dry etching.

11. (Currently Amended) A method according to claim 9, wherein said solid layer is provided with a discharge port pattern ~~on-the~~a liquid flow path pattern.

12. (Currently Amended) An ink jet recording head which comprises  
~~being a head produced by an ink jet recording head producing a~~ method according to any of claims 1 to 11.